

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant:	Hong Jyh Li	Examiner:	Phillip A. Johnston
Serial No.:	10/816,503	Group Art Unit:	2881
Filed:	April 1, 2004	Docket No.:	2004P51130US/I331.128.101
Title:	PLASMA ION IMPLANTATION SYSTEM		

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**RESPONSE**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

This Response is in reply to the Non-Final Office Action mailed January 12, 2007.